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Park et al.

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(54) **APPARATUS FOR ETCHING SUBSTRATE
AND FABRICATION LINE FOR
FABRICATING LIQUID CRYSTAL DISPLAY
USING THE SAME**

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patent is extended or adjusted under 35
U.S.C. 154(b) by 907 days.

This patent is subject to a terminal dis-
claimer.

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CPC **G02F 1/1303** (2013.01); **H01L 21/6708**
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(58) **Field of Classification Search**

None

See application file for complete search history.

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(57) **ABSTRACT**

A substrate etching apparatus includes: a cassette to receive a
substrate that has finished a previous process, and transfer the
substrate; a first robot to take the substrate out of the cassette;
a second robot to receive the substrate from the first robot and
move the substrate mounted thereon vertically up and down;
an etching cassette comprising a support to support the sub-
strate and a holder to fix the substrate loaded from the second
robot; a cassette fixing unit to fix at least one or more etching
cassettes and being rotated at a pre-set angle to allow the
substrate to be disposed perpendicular to the ground; and an
etching unit to etch the substrate disposed perpendicular to
the ground by the cassette fixing unit.

19 Claims, 13 Drawing Sheets

